## **Amendments to the Claims:**

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1-17. (Canceled)

comprises

\_\_\_\_\_bringing the array of micro-tips and the memory support into contact with a predetermined pressure, which is insufficient to cause a deformation representative of a data to be recorded, before the selective actuation of the micro-tips for data recording, said pressure enabling the dispersion of the dimensions heights of the micro-tips of the array of

19. (Currently Amended) Method The method according to claim 18, wherein data recording is of electric type.

micro-tips to be absorbed by the deformable memory layer.

- 20. (Currently Amended) Method The method according to claim 18, wherein data recording is of thermal type.
  - 21. (Canceled)
- 22. (Currently Amended) Recording A recording device for implementation of the method according to claim 18, comprising comprising:

an array of micro tips arranged in a plane facing a memory support, comprising a
stack of thin layers with at least one deformable memory layer, means for absorbing the
dispersion of the dimensions-heights of the micro-tips of the array array; and
means for recording by the selective actuation of the micro-tips,
wherein the deformable memory layer constitutes said means for absorbing when the
memory support and the array of micro-tips are brought into contact, at said predetermined
pressure, which is insufficient to cause a deformation representative of a data to be recorded,
the micro-tips, having an apex of nanometric dimension, being fixed directly onto one
and the same support substrate.

- 23. (Currently Amended) <u>Device The device according to claim 22</u>, wherein the memory layer is deposited on a flexible layer deposited on the substrate.
- 24. (Currently Amended) <u>Device The device according to claim 23</u>, wherein the flexible layer is made of polymer.
- 25. (Currently Amended) Device The device according to claim 24, wherein the flexible layer is made of photoresist.
- 26. (Currently Amended) <u>Device The device according to claim 23</u>, wherein the flexible layer is a glue of controlled hardness.
- 27. (Currently Amended) Device The device according to claim 23, wherein the flexible layer is made of elastomer silicone.
- 28. (Currently Amended) <u>Device-The device according to claim 23</u>, wherein the flexible layer has a thickness of about a few micrometers.
- 29. (Currently Amended) <u>Device-The device according to claim 23</u>, wherein the flexible layer is conducting.
- 30. (Currently Amended) Device The device according to claim 23, <u>further</u> comprising:

	an additional conducting layer between the memory layer and the flexible
layer.	
31.	(Currently Amended) Device The device according to claim 22, wherein the
memory layer has a thickness of less than one micrometer.	
32.	(Currently Amended) Device The device according to claim 22, further
comprising comprising:	
	an interface layer with the micro-tips, covering the memory layer.
33.	(Currently Amended) Device-The device according to claim 22, wherein the
substrate is made of silicon.	
34.	(Currently Amended) Device The device according to claim 22, wherein the

substrate is made of plastic material with a thickness of less than one millimeter.